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MEMS/NEMS Sensors: Fabrication and Application, Volume II

Guest Editors:

Prof. Dr. Goutam Koley

Department of Electrical and
Computer Engineering, Clemson
University, Clemson, SC 29634,
USA

Dr. Ifat Jahangir

Intel Corporation, OR 97124, USA

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Message from the Guest Editors

Despite a long history of development, the fabrication of novel MEMS/NEMS devices still poses unique challenges due to their requirement for a suspended geometry. Many new fabrication techniques have been proposed to overcome these challenges. However, further development of these techniques is still necessary, as newer materials such as compound semiconductors and two-dimensional materials are finding their way in various MEMS/NEMS applications, with more complex structures and potentially smaller dimensions.

For this Special Issue, you are invited to submit contributions describing developments in the broad area of MEMS/NEMS-based sensors ranging from nanoscale to macroscale in dimensions and operating over a large range of frequencies, from GHz to a few Hz. The scope of this Special Issue covers different types of individual MEMS/NEMS sensors—made with traditional and emerging materials by employing various transduction schemes, sensor networks, and multimodal data fusion—theory and applications,



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Special Issue



Editor-in-Chief

Message from the Editor-in-Chief

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Micromachines Editorial Office
MDPI, St. Alban-Anlage 66
4052 Basel, Switzerland

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